



Serial No. 09/963,482

SEC.843

Amendment dated 21 May 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Hee-Tae LEE et al.

Group Art Unit: 2125

Serial No.: 09/963,482

Examiner: Michael D. MASINICK

Filed: 27 September 2001

CHEMICAL VAPOR DEPOSITION
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AMENDMENT UNDER 37 C.F.R. § 1.111

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, Mail Stop **Fee Amendment**
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

In response to the Office Action dated 21 January 2004, the period for response to which is hereby being extended by the accompanying Petition and Petition Fee through 21 May 2004, please amend the above-identified patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.